

Art Unit: 1731  
Serial No: 10/086,190

42. (New) An apparatus for coating a substrate having a complex outer surface by means of a chemical gas phase separation process, the apparatus comprising:

a first filament holder spaced apart and parallel to a second filament holder, the first filament holder including a first filament clamp, the second filament holder including a second filament clamp, the first and second filament holders being spaced apart by a predetermined distance;

a plurality of filaments having first and second ends and having a length greater than the predetermined distance, the first end of each of the plurality of filaments clamped in the first clamp and the second end of each of the plurality of filaments clamped in the second clamp, such that the weight of the plurality of filaments provides a suspended portion of the plurality of the filaments;

wherein the distance between each filament and the substrate is substantially the same and the plurality of filaments at least partially surround and conform to the outer surface of the complex substrate.--

#### REMARKS

By present amendment, claims 5 and 12-15 were canceled, claims 16-42 were added, and claims 1-4 and 6-11 were amended to more particularly point out and distinctly claim the subject matter that the Applicants regard as the invention. No new matter has been added. Thus, after entry of this Amendment, claims 1-4, 6-11 and 16-42 will be pending in the application.

#### CONCLUSION

In view of the foregoing amendments and remarks, the Applicants respectfully submit that all of the claims pending in the above-identified application are in condition for examination, and corresponding action is respectfully solicited.

Art Unit: 1731  
Serial No: 10/086,190

If the Examiner believes that a telephone conference would further the prosecution of the subject application, Applicants' attorney may be contacted by telephone at the number indicated below to schedule such an interview.

The U.S. Patent and Trademark Office is authorized to charge any additional fees incurred as a result of the filing hereof or credit any overpayment to our deposit account #19-0120.

Respectfully submitted,  
MATTHEE, Thorsten et al., Applicants

Dated: June 17, 2003

By: 

Michele J. Young, Reg. No. 43,299  
Applicants' Attorney  
SALTER & MICHAELSON  
321 South Main Street  
Providence, Rhode Island 02903  
Telephone: 401/421-3141  
Facsimile : 401/861-1953  
Customer No. 000987

Art Unit: 1731  
Serial No: 10/086,190

**Version with marking to show changes to claims**

1. (Amended Once) An [A]apparatus for coating a substrate having a complex outer surface by means of a chemical gas phase separation process, [characterised by a not merely two-dimensional arrangement of the filaments (5, 17, 26) at least partially surrounding the substrate to be coated, but] the apparatus comprising:

[a three-dimensional] an arrangement of filaments adaptable to at least partially surround and conform to the outer surface of the complex [in respect of the] substrate, wherein the distance between the filaments and the substrate remains substantially the same.

2. (Once amended) The [A]apparatus according to claim 1, [characterised in that] wherein the filaments [(5, 17, 26)] completely surround the substrate to be coated.

3. (Once amended) The [A]apparatus according to claim 2, [characterised in that the] wherein a suspension of the filaments matches the shape of the substrate to be coated [or of a tool (15, 22)].

4. (Once amended) The [A]apparatus according to claim 3, [characterised in that] wherein the filaments are [at a spacing of] spaced 1mm to 30mm from the substrate [surface] to be coated.

6. (Once amended) The [A]apparatus according to claim 1, [characterised in that] wherein the filaments [(17)] are clamped at both ends thereof in holders [(18, 19)] arranged parallel with each other, and [that] a curvature is formed by the dead weight of the filaments [(17)].

Art Unit: 1731  
Serial No: 10/086,190

7. (Once amended) The [A]apparatus according to claim 6, [characterised in that] further comprising radiation screens [(23) are] arranged on the holders [(18, 19)] as a protection from heat loss.

8. (Once amended) The [A]apparatus according to claim 6, [characterised in that] wherein said holders [(24)] have slots [(25)] for flexibly clamping in filaments [(17)] of different lengths.

9. (Once amended) The [A]apparatus according to claim 7, [characterised in that] wherein said holders [(24)] have slots [(25)] for flexibly clamping in filaments [(17)] of different lengths.

10. (Once amended) The [A]apparatus according to claim[s] 1, [characterised in that] wherein the filaments [(26)] are arranged in two rows in concentric circles, [so that they are] so as to form an inner row of filaments and an outer row of filaments, the filaments of the inner row being arranged respectively in gaps between projections [(27) from] of the [tool (28) or] substrate [in the inner row (29)] and the filaments of the outer row being arranged proximate outer ends of the projections, in gaps between filaments in the [outer] inner row of filaments [(30)].

11. (Once amended) The [A]apparatus according to claim [1] 6, [characterised in that] wherein said holders comprise filament retainers [(8, 16) and the filament retaining ring (6) of the half-shells (2, 3) or holders (18, 19) and/or a clamping ring (9) of the short-circuiting ring (4) are provided tapering with] said filament retainers including a bevelled wall [(13, 14)].